



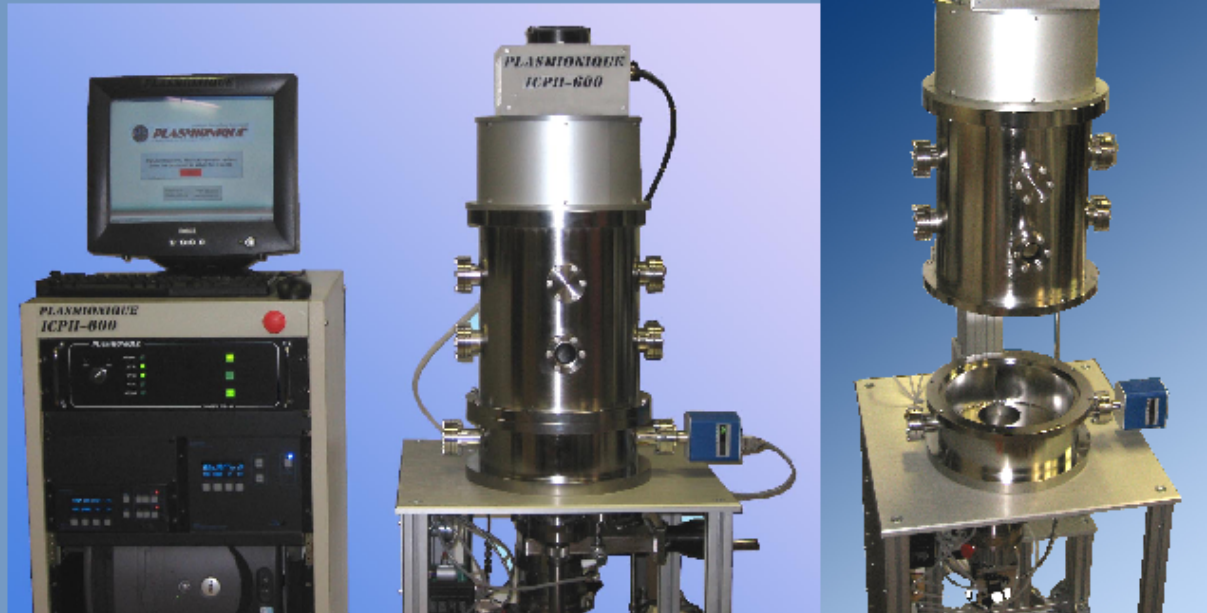
Advancing Plasma-Based Technologies

PLASMIONIQUE

À l'Avant-Garde des Technologies Plasma

ICPII-600

A Multi-Functional Inductively Coupled Plasma Reactor



**Highly Versatile PECVD System with an Integrated Patented Design for Pulsed Plasma Ion Implantation.
Ideal experimental system for Research and Process Development**

System Equipped with:
Turbo and Mechanical pumps
Full Pressure Range Gauges
Multiple Mass Flow Controllers
Throttle valve
Computer Controlled Operation with
Integrated Safety and Control System

www.plasmionique.com

Info@plasmionique.com